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A Track (Modified)	Atty Docket No. NOVLP037C1/NVLS- 000519C1	Application No.: 10/773,821
Information Disclosure Statement By Applicant	Applicant: van Schravendijk et al.	
	Filing Date February 5, 2004	Group 2813

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
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Foreign Patent or Published Foreign Patent Application

Examiner		Document		Publication	Country or	\angle		Sub-	Trans	lation
Initial	No.	No.		Date	Patent Office		Class	class	Yes	No
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Other Documents

Examiner					
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication			
M	Cl	Li et al., "Methods of Forming Moisture Barrier for Low K Film Intergration with Anti-Reflective Layers", Novellus Systems, Inc., Appln. No. 11/168,013, filed June 27, 2005, pages 1-25. [NOVLP128/NVLS-3043]			
Any	C2	U.S. Office Action mailed October 24, 2002, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]			
My	C3	U.S. Office Action mailed May 21, 2003, from U.S. Application No. 09/990,197. [NOVLP037/NVLS-000519]			
Examiner	M	Date Considered 12/16/05			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.